







	MEMS at Bo	sch and Foundry History	СН	
	Milestones MEMS at Bosch			
	z 1987	Start of MEMS research activities		
	z 1989	Development section for MEMS		
	z 1992	Deep trench process developed (the "Bosch Pro	cess")	
	z 1993	First volume MEMS-product: Pressure sensor		
	z 1995	SOP micromachined mass flow sensor		
	z 1997	SOP micromachined accelerometer		
	z 1997	Start of component sales to external customers		
	z 1998	Silicon gyro in mass production		
	z 1999	Research Center Palo Alto founded		
	z 2002	Market introduction of 2 nd generation accelerom	eters	
	z 2002	More than 70 Mio MEMS-based sensors per yea	ar	
	z coming:	Hydrogen sensor, gas sensor, new applications		
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